

Title (en)

PRODUCTION METHOD FOR A SURFACE SENSOR, SYSTEM AND USE OF A SURFACE SENSOR

Title (de)

HERSTELLUNGSVERFAHREN FÜR EINEN OBERFLÄCHENSSENSOR, SYSTEM UND VERWENDUNG EINES OBERFLÄCHENSSENSORS

Title (fr)

PROCÉDÉ DE FABRICATION D'UN CAPTEUR SURFACIQUE, SYSTÈME ET UTILISATION D'UN CAPTEUR SURFACIQUE

Publication

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Application

**EP 09723994 A 20090323**

Priority

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Abstract (en)

[origin: WO2009118287A1] The invention relates to a surface sensor (100, 200), comprising a frequency-selective surface with periodically arranged THz structures (1), in particular THz resonance structures (1), which are sensitive to THz radiation, a polarization axis (3) being associated to each structure. In order to improve remote field characteristics, the invention provides that a THz structure (1) is configured asymmetrically and a group of two or more THz structures (1) have essentially centrosymmetrically aligned polarization axes (3) for forming a unit cell.

IPC 8 full level

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